









- Die power dissipation density remains approximately constant with the scaling down of feature size (*ITRS '99*)
- Interconnect Joule heating plays a very important role in the interconnect thermal profile
- By scaling, long global interconnects getting more closer to the substrate

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![](_page_10_Figure_0.jpeg)

![](_page_10_Figure_1.jpeg)

![](_page_11_Figure_0.jpeg)

## Optimum Location of the Branching Point

 Using the temperature-dependent delay model, the optimal location of the branching point is calculated as:

$$\beta \int_{0}^{l} T(x) dx + l^{*} - A = 0$$
 A is a constant

•With a symmetric non-uniform thermal profile, the branching point is still at  $l^* = L/2$ 

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![](_page_12_Figure_0.jpeg)

Experimental Results					
	T <sub>line</sub> (x)	params	<i>l</i> = <i>l</i> *	l = L/2 skew%	
	T(x) = ax + b	T <sub>H</sub> =170, T <sub>L</sub> =90	1042	5.42	
	$a = \frac{T_H - T_L}{L}  b = T_L$	T <sub>H</sub> =170, T <sub>L</sub> =110	1032	3.98	
		T <sub>H</sub> =170, T <sub>L</sub> =130	1021	2.65	
	$T(x) = a \cdot e^{-bx}$	T <sub>H</sub> =170, T <sub>L</sub> =90	957.5	5.24	
	$b = \frac{1}{L} \ln(\frac{T_H}{T_L})  a = T_H$	T <sub>H</sub> =170, T <sub>L</sub> =110	968.66	3.63	
		T <sub>H</sub> =170, T <sub>L</sub> =130	979.5	2.40	
	$-(x-\mu)^2$	μ=2000, σ=1000	1210	7.78	
	$T(x) = T_{\max} \cdot e^{\frac{-\frac{1}{2\sigma^2}}{2\sigma^2}}$	μ=1000, σ=400	1000	0.0	
		μ=300, σ=700	911	9.57	
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## Effects of Non-Uniform Temperature on EDA Tools and Techniques

 Interconnect non-uniform thermal profile can affect many design optimizations:

- Optimal layer assignment
- Buffer insertion
- Wire sizing
- Gate sizing

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![](_page_13_Figure_7.jpeg)

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